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Front Matter: Volume 11294

, "Front Matter: Volume 11294," Proc. SPIE 11294, Emerging Digital Micromirror Device Based Systems and Applications XII, 1129401 (14 April 2020); doi: 10.1117/12.2570457

SPIE.

Event: SPIE OPTO, 2020, San Francisco, California, United States

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Emerging Digital Micromirror Device Based Systems and Applications XII

**John Ehmke
Benjamin L. Lee**
Editors

**4–5 February 2020
San Francisco, California, United States**

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SPIE

Volume 11294

Proceedings of SPIE 0277-786X, V. 11294

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Emerging Digital Micromirror Device Based Systems and Applications XII, edited by John Ehmke, Benjamin L. Lee,
Proc. of SPIE Vol. 11294, 1129401 · © 2020 SPIE · CCC code: 0277-786X/20/\$21 · doi: 10.1117/12.2570457

Proc. of SPIE Vol. 11294 1129401-1

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Author(s), "Title of Paper," in *Emerging Digital Micromirror Device Based Systems and Applications XII*, edited by John Ehmke, Benjamin L. Lee, Proceedings of SPIE Vol. 11294 (SPIE, Bellingham, WA, 2020) Seven-digit Article CID Number.

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510633513
ISBN: 9781510633520 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
SPIE.org
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